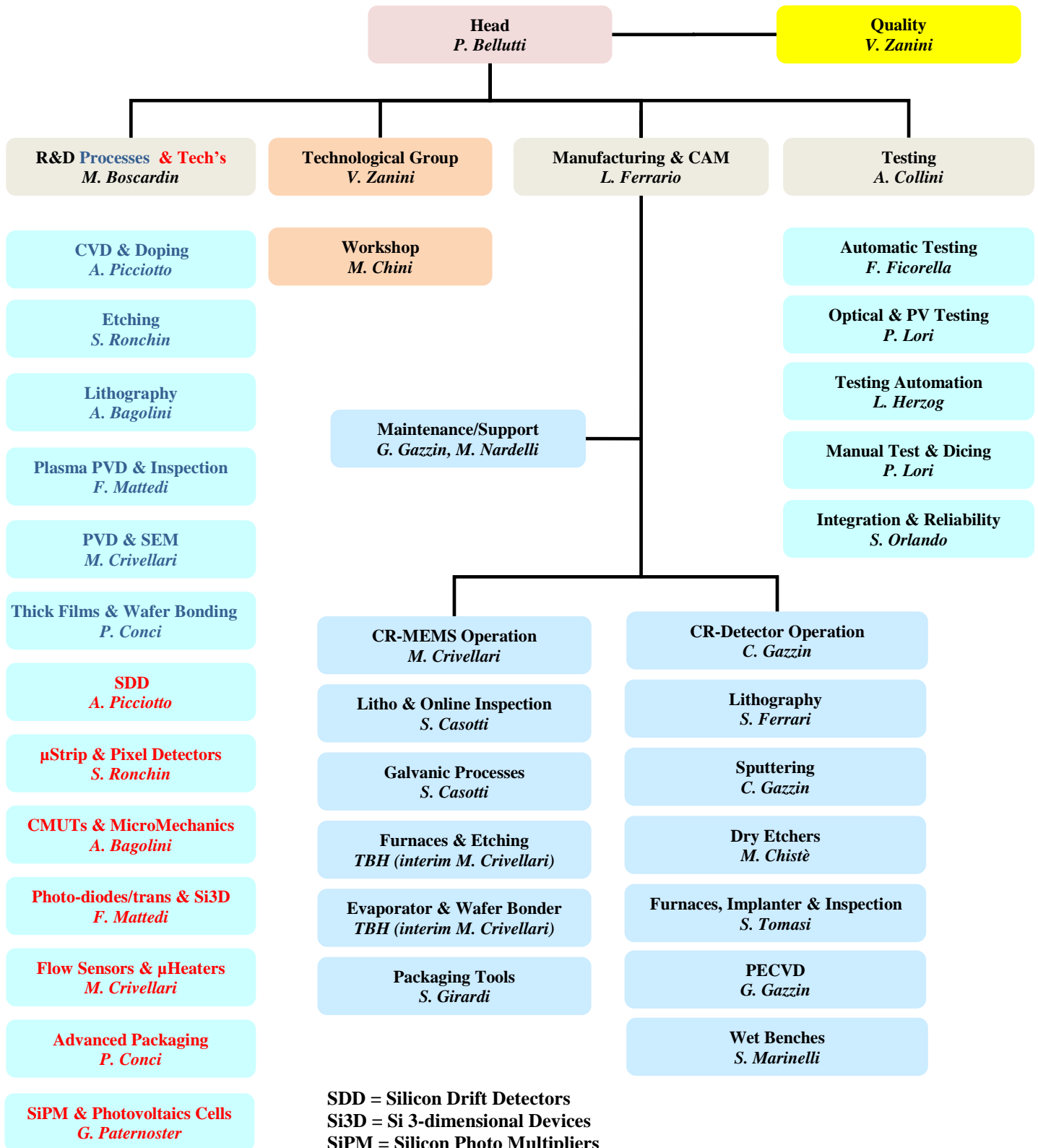


MTLab Organizational Chart



SDD = Silicon Drift Detectors
Si3D = Si 3-dimensional Devices
SiPM = Silicon Photo Multipliers
CMUT = Capacitive Micromachined Ultrasonic Transducers
PV = Photovoltaics
PVD = Physical Vapour Deposition
CVD = Chemical vapour Deposition
SEM = Scanning Electron Microscopy
CAM = Computer Aided manufacturing
CR = Clean Room
MEMS = Micro-Electro-Mechanical Systems